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Front Matter: Volume 10514

, "Front Matter: Volume 10514," Proc. SPIE 10514, High-Power Diode Laser Technology XVI, 1051401 (23 March 2018); doi: 10.1117/12.2322760

SPIE.

Event: SPIE LASE, 2018, San Francisco, California, United States

PROCEEDINGS OF SPIE

High-Power Diode Laser Technology XVI

Mark S. Zediker
Editor

29–30 January 2018
San Francisco, California, United States

Sponsored and Published by
SPIE

Volume 10514

Proceedings of SPIE 0277-786X, V. 10514

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

High-Power Diode Laser Technology XVI, edited by Mark S. Zediker, Proc. of SPIE Vol. 10514,
1051401 · © 2018 SPIE · CCC code: 0277-786X/18/\$18 · doi: 10.1117/12.2322760

Proc. of SPIE Vol. 10514 1051401-1

The papers in this volume were part of the technical conference cited on the cover and title page. Papers were selected and subject to review by the editors and conference program committee. Some conference presentations may not be available for publication. Additional papers and presentation recordings may be available online in the SPIE Digital Library at SPIDigitalLibrary.org.

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in *High-Power Diode Laser Technology XVI*, edited by Mark S. Zediker, Proceedings of SPIE Vol. 10514 (SPIE, Bellingham, WA, 2018) Seven-digit Article CID Number.

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510615137

ISBN: 9781510615144 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445

SPIE.org

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Introduction

This year the conference was expanded to start the conversation on the new high power blue laser diode technology which is emerging as a new tool for the industrial markets. The conference included several talks on the new high power blue products aimed at welding copper and other materials with high reflectivity in the IR compared to the blue. Attendance was standing room only and discussions were filled with questions about the technology and its applications. We plan to expand this section of the conference next year and expect a number of new companies to join the development of this new and exciting technology.

The high-power IR laser diode talks also did not disappoint, the march to higher and higher brightness laser diode products continue. The results were best summarized in a talk by nLIGHT Corporation (United States) where they plotted the improvement in brightness as a function of time. The brightness of the diode laser product line have now eclipsed the brightness of high power lamp pumped solid state lasers and are starting to challenge the multi-mode diode pumped solid state lasers. Higher power bars, better cooling methods and better micro-optics were all part of the conference as well.

Mark S. Zediker